

Appl. No. 10/009,910
Amdt. Dated September 22, 2004
Reply to Office Action of June 24, 2004

Attorney Docket No. 81839.0107
Customer No. 26021
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Makoto IIDA et al.

Serial No.: 10/009,910

Confirmation No.: 7347

Filed: December 12, 2001

For: SILICON WAFER, SILICON
EPITAXIAL WAFER, ANNEAL
WAFER AND METHOD FOR
PRODUCING THEM

Art Unit: 1765

Examiner: Matthew J. Song

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RESPONSE TO FINAL OFFICE ACTION

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Dear Sir:

In response to the Final Office Action of June 24, 2004, please enter and
consider the following Remarks/Arguments:

The Claims are reflected in the listing of claims, which begins on page 2 of
this paper.

Remarks/Arguments begin on page 4 of this paper.